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Ideal for process development or production in small substrate sizes or volumes, the BAK 501 comes with all the capability of its bigger brothers in the BAK family, at a footprint and cost to meet the tightest requirements. Simple process transfer to larger members of the BAK family makes future scale up simple. The BAK 501 can then be easily reconfigured for your next big idea.

**Complete range of process components**

The BAK 501 is compatible with Evatec's range of production proven process accessories including:

- The EBS 500 electron beam gun
- Thermal sources
- Sputter sources
- Back and front side heating
- Glow discharge cleaning
- Custom substrate holder and handling systems

**Professional process control**

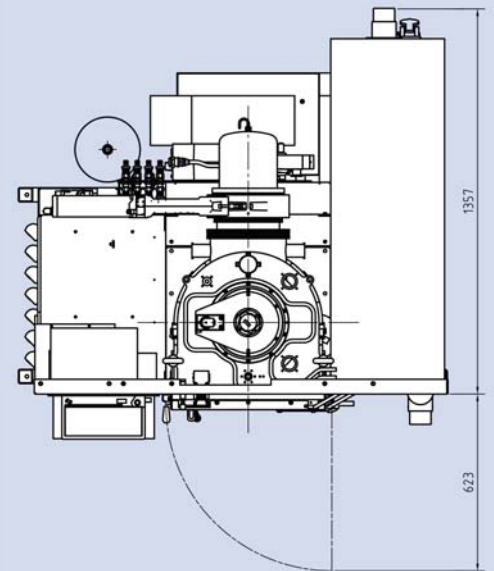
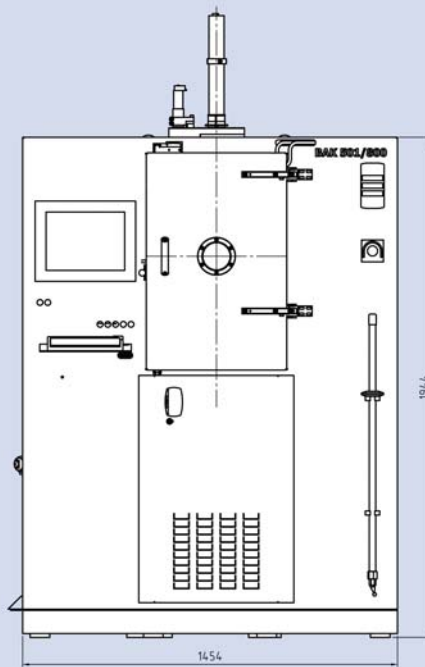
From pump down to system vent, Evatec's user friendly Khan platform is easy to configure and ensures all process sequences conform within strict limits for best overall repeatabilities and yields.

- Quartz and Optical Monitoring including broadband
- RGA integration possible
- Full SECS GEM compatibility

501

**Substrate size Capacity**

2 inch	●	Up to 32
4 inch	●	Up to 8
6 inch	●	Up to 4



**Footprint only 2 m<sup>2</sup>**

